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Docket No. AM1562D1

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of

YIQIONG WANG

Serial No.: 09/882,141

Filed: June 15, 2001

For: METHOD OF ETCHING HIGH ASPECT
RATIO OPENINGS IN SILICON

Confirmation No. 8856

Examiner: Umez-Eronini

Group Art Unit: 1765

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AMENDED RESPONSE UNDER 37 CFR 1.115

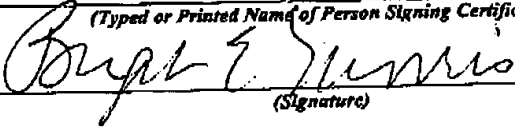
To: Assistant Commissioner for Patents
Washington, DC 20231

Sir:

In response to the office action of February 25, 2003, and a
Notice of Non-Compliant Amendment dated June 4m 2003, please
amend the above-identified application as follows.

OFFICIAL

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CERTIFICATE OF TRANSMISSION BY FACSIMILE (37 CFR 1.8)			Docket No. AM1562D1
Applicant(s): YIQIONG WANG			
Serial No. 09/882,141	Filing Date June 15, 2001	Examiner Umez-Eronini	Group Art Unit 1765
Invention: METHOD OF ETCHING HIGH ASPECT RATIO OPENINGS IN SILICON			
<p>I hereby certify that this <u>Amended Response under 37 CFR 1.115 (8pp)</u> (Identify type of correspondence) is being facsimile transmitted to the United States Patent and Trademark Office (Fax. No. <u>703-872-9310</u>) on <u>June 12, 2003</u> (Date)</p> <p style="text-align: right;">Birgit E. Morris (Typed or Printed Name of Person Signing Certificate)  (Signature)</p> <p style="text-align: center;">Note: Each paper must have its own certificate of mailing.</p>			

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